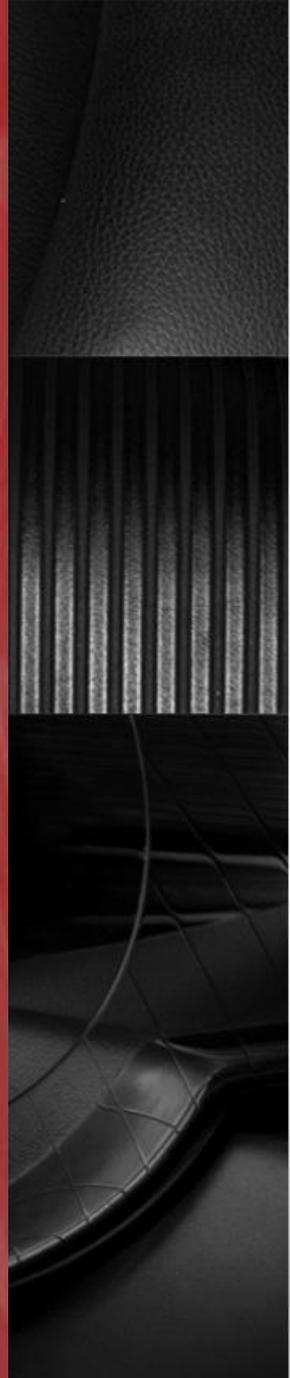


Lab 10: AFM

April 22-22

2016



Procedure

1) Understand

- Walk-through of the system, identifying important controls & hazards

2) Calibrate

- Generate calibration curve

3) Image samples

- MEMS device
- CD tracks
- Calibration grating

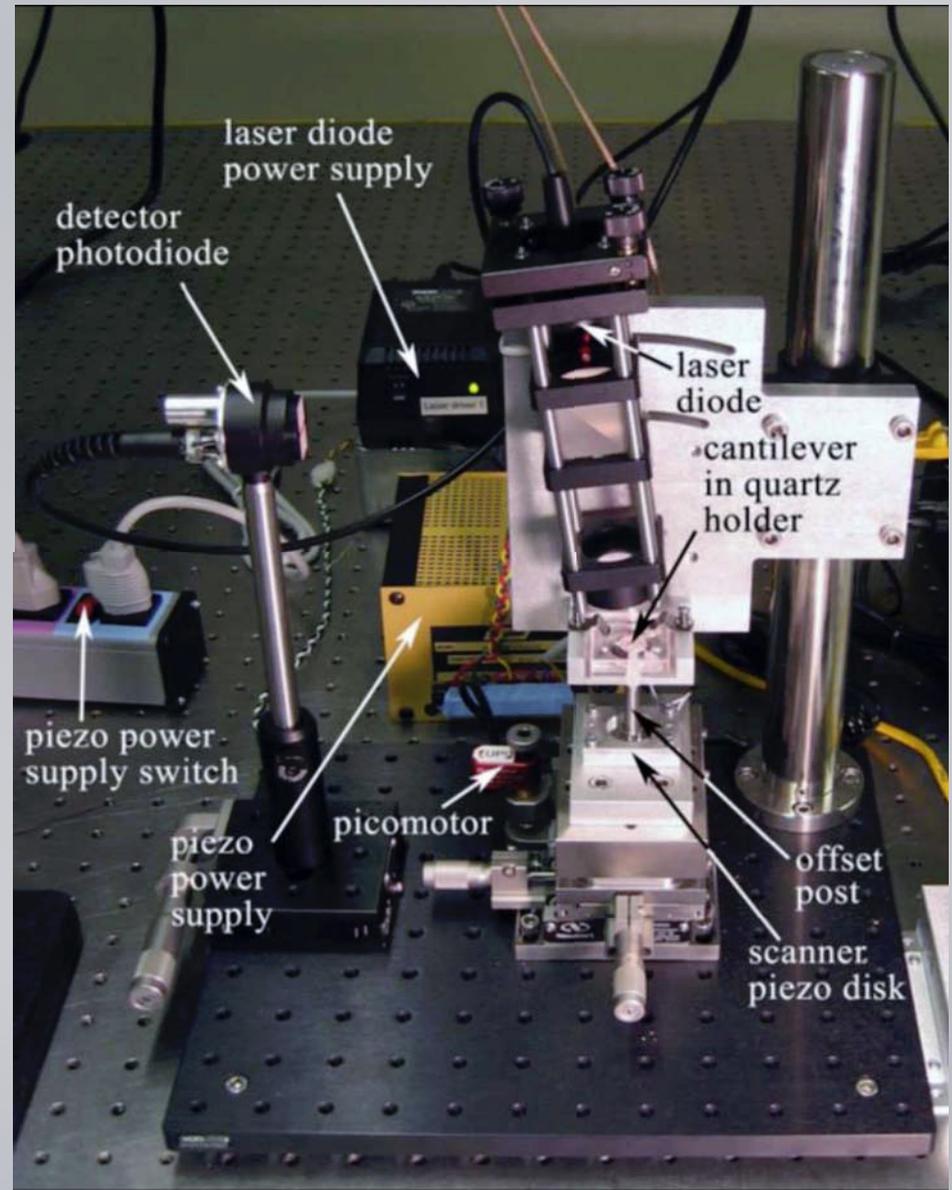


Image courtesy of Edward Boyden. Used with permission.

Our AFM Setup

- Piezo control of the sample

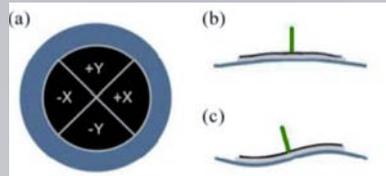


Image courtesy of Edward Boyden. Used with permission.

- Interdigitated fingers

- Diffraction pattern of dark & light spots called modes
- $\lambda = 635 \text{ nm}$ for laser – Do not stare into the laser!

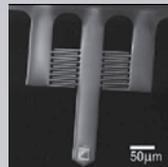


Image courtesy of Edward Boyden. Used with permission.

- Z-mod – switch DOWN

- Use for calibration

- Image mode – switch UP

- Use to measure samples

- Recommend “Print Screen” for data acquisition

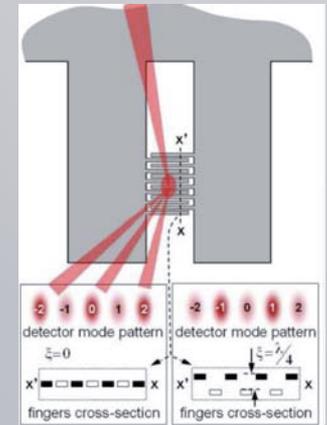


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Calibration in Z mod

- Goal: Relate detector's voltage signal to physical tip deflection
 - nm of tip bending per volt of signal
- Find good bias point when tip touches then releases
- Mode from fully bright to dark (peak to trough on \sin^2 function) when fingers deflect a distance of $\lambda/4$, about 160 nm
 - Use this to quantify horizontal axis
 - Calculate slope, nm/V
- Need to correct slope as interdigitated finger is not tip deflection
 - Use equation for simple rectangular beam with applied end-load
 - $A_{\text{corr}} = 2/(3m_{\text{id}}^2 - m_{\text{id}}^3)$, $m_{\text{id}} = L_{\text{ID}}/L_{\text{T}}$
- Once you calibrate do not move any optics!

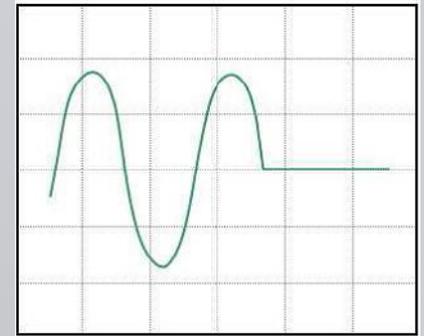


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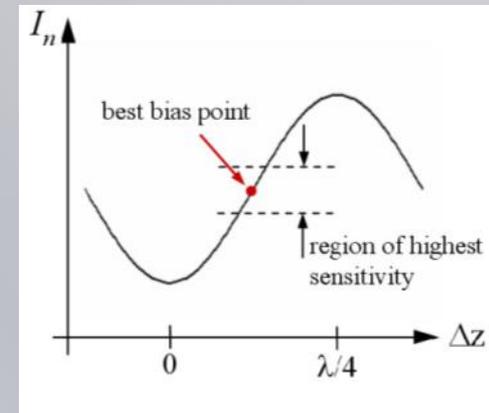


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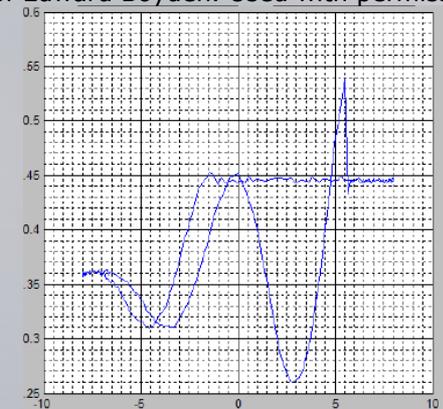


Image Mode

- Stop z-mod
- Switch sample, if needed
- Engage tip
- Start imaging!
- Capture scans to get image dimensions
- Capture scope view scans to give feature height data

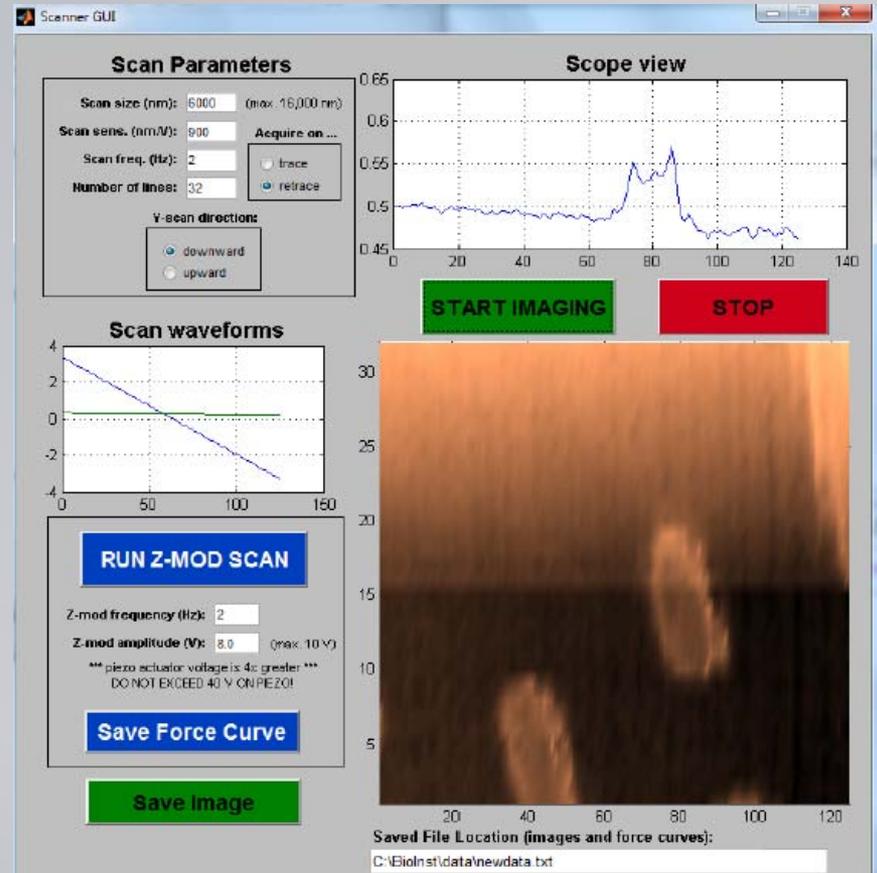


Image courtesy of Edward Boyden. Used with permission.

Thermal Noise

- 1) Calibrate – can use the same factor as part 1 if no changes to system
 - Calibration using bare Si wafer, run z-mod
- 2) Increase gain
 - Make note of gain change and adjust calibration factor
- 3) Measure thermal noise
 - Run Labview Spectrum Analyzer tool
 - Observe 1/f noise, thermomechanical “white” noise, and resonance peak(s)
- 4) Perform calculation and check values
 - Calculate Q, ratio of energy stored/energy dissipated
 - Calculate $\langle x^2 \rangle$, spectral density of cantilever deflection in flat region below resonance peak (white noise region)
 - Solve expression for k, and calculate experimental spring constant– check units and compare to given value in lab notebook
 - $Q = k/(b\omega_0)$, $\langle f_n^2 \rangle = 4k_b T b = k^2 \langle x^2 \rangle$

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Spring 2016

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